

DETAILS of PROCUREMENT PLAN for MAJOR EQUIPMENTS in next 3 to 5 Years

Sl.No.	Name of the Equipment
1	UHV based multi-purpose thin film deposition system
2	Close cycle Cryocooler based Portable liquid Helium plant
3	High resolution UV mask Aligner
4	Low temperature cryostat with high magnetic field
5	Ultrashort pulse fiber laser and MIR Optical Spectrum Analyzer
6	Switching Magnet and beamline for with scanner for ion implantation
7	ALD System
8	High temperature wettability setup
9	60 femtosecond one box amplifier system for time-resolved MOKE system along with accessories
10	RHEED system
11	Low temperature Ferromagnetic resonance spectrometer
12	Electron Energy-Loss Spectroscopy (EELS)
13	Cryo-transmission electron microscope (Cryo-TEM)
14	Bridgman furnace
15	Tunable CW laser with ultra-narrow frequency noise at MIR
16	Automated Probe station for IV and CV characteristics
17	High Resolution Mass Spectrometer
18	Single Molecule Super Resolution Fluorescence Microscope
19	X-ray Photo electroscopy instrument
20	Online/differential electrochemical Mass Spectroscopy instrument (DEMS)
21	One Box Femto-second Amplified Laser and Optical Parametric Amplifier (OPA) for Femto-second Transient Absorption Spectrometer.
22	Femtosecond UV-Vis Transient Spectrum analyser
23	Steady state and time-resolved (ps) Fluorescence Spectrometer with electroluminescence facility
